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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/673,376	09/30/2003	John A. Hughes	240720US6YA	4362
22850	7590 06/01/2006		EXAMINER	
OBLON, SPIVAK, MCCLELLAND, MAIER & NEUSTADT, P.C.			ARANCIBIA, MAUREEN GRAMAGLIA	
1940 DUKE S ALEXANDR	IA, VA 22314		ART UNIT	PAPER NUMBER
	,		1763	
			DATE MAILED: 06/01/2006	

Please find below and/or attached an Office communication concerning this application or proceeding.

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		Application No.	Applicant(s)	
Office Action Summary		10/673,376	HUGHES ET AL.	
		Examiner	Art Unit	
		Maureen G. Arancibia	1763	
Period fo	The MAILING DATE of this communication apported to the second section apport.	pears on the cover sheet with the	correspondence address	
WHIC - Exter after - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING Donsions of time may be available under the provisions of 37 CFR 1.11 SIX (6) MONTHS from the mailing date of this communication. Period for reply is specified above, the maximum statutory period ver to reply within the set or extended period for reply will, by statute reply received by the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATIO 36(a). In no event, however, may a reply be ti will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONI	N. mely filed the mailing date of this communicat ED (35 U.S.C. § 133).	
Status				
2a)⊠	Responsive to communication(s) filed on <u>14 M</u> This action is <b>FINAL</b> . 2b) This Since this application is in condition for allowar closed in accordance with the practice under E	action is non-final. nce except for formal matters, pr		is
Dispositi	ion of Claims			
5) □ 6) ⊠ 7) □ 8) □ Applicati 9) □ 10) □	Claim(s) 1-39 is/are pending in the application 4a) Of the above claim(s) 2,4-10,12-17,19,21 a Claim(s) is/are allowed.  Claim(s) 1,3,11,18, 20 and 22 is/are rejected.  Claim(s) is/are objected to.  Claim(s) are subject to restriction and/o ion Papers  The specification is objected to by the Examine The drawing(s) filed on is/are: a) acc Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examine	and 23-39 is/are withdrawn from a relection requirement.  er. epted or b) □ objected to by the drawing(s) be held in abeyance. Settion is required if the drawing(s) is old	Examiner. ee 37 CFR 1.85(a). ojected to. See 37 CFR 1.121	
		Camiller. Note the attached Office	e Action of form 7 10-132.	
12)□ a)l	Acknowledgment is made of a claim for foreign All b) Some * c) None of:  1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority document application from the International Bureau See the attached detailed Office action for a list	s have been received. s have been received in Applicative rity documents have been receive u (PCT Rule 17.2(a)).	tion No red in this National Stage	
2)  Notice  No	t(s) se of References Cited (PTO-892) se of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) r No(s)/Mail Date	4) Interview Summar Paper No(s)/Mail D 5) Notice of Informal 6) Other:		

#### **DETAILED ACTION**

## Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 1, 3, 11, 18, 20, and 22 are rejected under 35 U.S.C. 102(b) as being anticipated by U.S. Patent 6,367,412 to Ramaswamy et al.

In regards to Claims 1 and 18, Ramaswamy et al. teaches a semiconductor manufacturing system (Figure 1) for processing a substrate 14 using a plasma process, comprising: a processing chamber 10 configured to facilitate said plasma process (Column 1, Lines 10-11 and 45-51); a substrate holder 12 configured to support said substrate 14 (Figure 1); a gas distribution system 22 coupled to said processing chamber via plasma source 20 and configured to introduce a process gas to said processing chamber; a plasma source 20 coupled to the processing chamber and configured to generate a plasma in said processing chamber (by forming a plasma and delivering it to the processing chamber; Column 1, Lines 61-64); and a processing element 50 (Figure 3) coupled to the plasma source (Column 4, Lines 24-25) and therefore (fluidly) coupled to the gas distribution system 22 and the processing chamber 10 as broadly recited in the claim; said processing element comprising a passive component 56 (low chemical reactivity with the plasma; Column 4, Lines 32-38) and an active component (catalyst additive) included as part of said passive component

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(included within the porous tube) and configured to alter the chemistry of the plasma process when exposed to the plasma process (effective in catalyzing and thus increasing the yield of almost any chemical reaction). (Column 5, Lines 37-63)

The semiconductor manufacturing system would be inherently structurally capable of performing plasma processing that would cause the passive component to be eroded when exposed to the plasma process, based on the processing gas selected and other process settings. The effects of the plasma processing performed in the system are process limitations that do not represent structural limitations of the apparatus recited. It has been held that a claim containing a "recitation with respect to the manner in which a claimed apparatus is intended to be employed does not differentiate the claimed apparatus from a prior art apparatus" if the prior art apparatus teaches all the structural limitations of the claim. Ex parte Masham, 2 USPQ2d 1647 (Bd. Pat. App. & Inter. 1987) This rejection is based on the fact the apparatus structure taught above has the inherent capability of being used in the manner intended by the Applicant. When a rejection is based on inherency, a rejection under 35 U.S.C. 102 or U.S.C. 103 is appropriate. (See *In re Fitzgerald* 205 USPQ 594 or MPEP 2112).

In regards to Claims 3, 11, 20, and 22, the active component comprises a distribution of solid particles (the metal phase remains intact; Column 5, Lines 37-51) encapsulated within said passive component (The catalyst may be included in the tube being sintered or otherwise cast...The catalyst may be implanted into the porous ceramic; Column 5, Lines 53-63), as broadly recited in the claims.

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## Response to Arguments

3. Applicant's arguments with respect to claims 1, 3, 11, 18, 20, and 22 have been considered but are most in view of the new ground(s) of rejection.

### Conclusion

- 4. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. U.S. Patent 5,059,292 to Collins et al. teaches a plasma processing apparatus (ex. Figure 4d) including a processing element 71 comprising a passive component (porous foamed structure) and an active component (source material) that is included as part of the passive component and configured to alter the chemistry of a plasma process. (Abstract)
- 5. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of

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the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Maureen G. Arancibia whose telephone number is (571) 272-1219. The examiner can normally be reached on core hours of 10-5, Monday-Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on (571) 272-1435. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Maureen G. Arancibia Patent Examiner

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Maureen

Parviz Hassanzadeh Supervisory Patent Examiner

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